



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
(Case No. MMD98010CONDIV)

In the Application of:)	
)	
Vlasta Brusic Kaufman et al.)	Examiner: George Goudreau
)	
Serial No. 10/616,335)	
)	Group Art Unit: 1763
Filed: July 9, 2003)	
)	
Title: Chemical Mechanical Polishing)	
Slurry Useful for Copper)	
Substrates)	

REPLY TO MARCH 25, 2005 OFFICIAL ACTION

Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

This is a Reply to the March 25, 2005 Official Action for the above-captioned U.S. patent application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.

Appendix A which includes a copy of a Terminal Disclaimer filed in this case follows page 6 of this Reply.